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S-curve engineering for ON-state performance using anti-ferroelectric/ferroelectric stack negativecapacitance FinFET

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Abstract

This work investigates the S-curve engineering by exploiting the anti-ferroelectric (AFE)/ferroelectric (FE) stack negative-capacitance FinFET (NC-FinFET) to improve both the subthreshold swing and ON-state current (I_{ON}). Our study indicates that the AFE/FE gate-stack can theoretically achieve surprising improvements to the OFF-state current (IOFF) and ION relative to IRDS projections. There is significant long-term advantage to IC power consumption and speed if materials with certain AFE and FE characteristics can be developed and introduced into IC manufacturing.